



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki KOMATSUDA

Application No.: 09/697,639

Filed: October 27, 2000

Group Art Unit: 2851

Examiner: R. Fuller

Docket No.: 105193.01

For: EXPOSURE APPARATUS AND METHOD OF FABRICATING A MICRO DEVICE
USING THE EXPOSURE APPARATUS

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AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

Further to the Request For Continued Examination (RCE) filed on November 19, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please replace claims 16, 19, 22, 33 and 34 as follows:

16. (Amended) The exposure apparatus of claim 1, wherein the illumination optical system comprises:

a radiation source that outputs a radiation beam;

a reflective optical integrator that makes uniform an illumination distribution of radiation from the radiation beam; and

a radiation guiding optical system arranged in an optical path between the radiation source and the reflective optical integrator, and that guides the radiation beam from the radiation source to the reflective optical integrator.